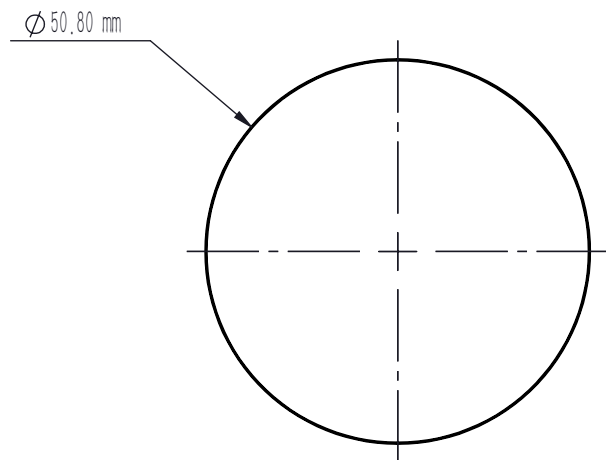
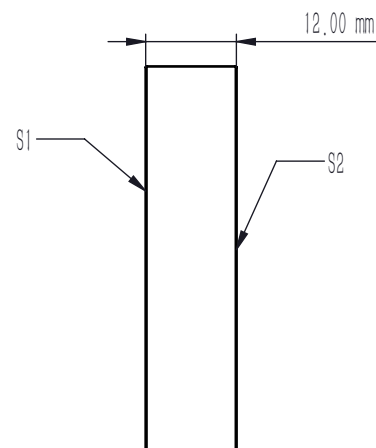
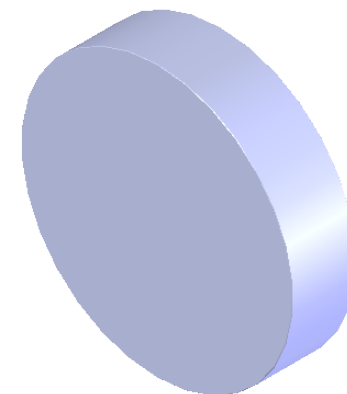
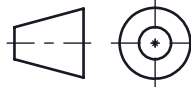




NOTES

- COATING(S1): LOW GDD COATING
 $R_s > 99\% @ 340 \text{ nm} - 425 \text{ nm}, AOI = 45^\circ$,
 $R_p > 99\% @ 360 \text{ nm} - 400 \text{ nm}, AOI = 45^\circ$;
- GDD:
 $|GDD_s| < 30 \text{ fs}^2 @ 340 \text{ nm} - 425 \text{ nm}, AOI = 45^\circ$,
 $|GDD_p| < 30 \text{ fs}^2 @ 360 \text{ nm} - 400 \text{ nm}, AOI = 45^\circ$;
- CLEAR APERTURE: $> 90\% CA$
- SURFACE QUALITY(S/D)(S1): 20/10
- SURFACE FLATNESS(S1): $\lambda / 10 @ 632.8 \text{ nm}$
- PARALLELISM(S1, S2): $< 10 \text{ arcsec}$
- CHAMFER: $< 0.1 \text{ mm}, 45^\circ$
- THICKNESS TOLERANCE: $\pm 0.1 \text{ mm}$
- DIAMETER TOLERANCE: $+0.0 \text{ mm} / -0.1 \text{ mm}$
- BACK SURFACE(S2): POLISHED

DRAWING PROJECTION 			LBTEK			
	NAME	DATE	UFPM20—UVB			
DRAWN	ZWANG	JUN./8th/26	ULTRAFAST MIRROR $\varnothing 50.8 \text{ mm} \times 12 \text{ mm}, 340 - 425 \text{ nm}$			
APPROVAL	WCHENG	JUN./8th/26	MATERIAL	WEIGHT	SCALE	REV
FOR INFORMATION ONLY NOT FOR MANUFACTURING PURPOSES			UVFS	26.5 g	1:1	A